

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Application No.

09/611,037

Applicant:

Kuthi, et al.

Filed:

July 6, 2000

Title: :

METHOD FOR IMPLEMENTING A SEMICONDUCTOR PROCESS CHAMBER

**ELECTRODE** 

TC/A.U.

1763

Examiner

Alejandro Mulero, L.

Atty. Docket No.

LAM1P077A

Date:

April 24, 2003

: April 2

CERTIFICATE OF MAILING

**PATENT** 

I hereby certify that this correspondence is being deposited with the United States Postal Service as First Class Mail in an envelope addressed to: Commissioner for Patents, Washington, DC 20231

i selva III

Signed:

Honorable Commissioner for Patents Washington, D.C. 20231

## **AMENDMENT**

Sir:

Applicants submit this paper in response to the Office Action dated January 24, 2003. The period for response extends to April 24, 2003. Please enter the following amendments and remarks:

Amendments to the Claims are reflected in the listing of claims which begins on page 2 of this paper.

Remarks/Argument begins on page 8 of this paper.